

CROSS REFERENCE TO RELATED APPLICATION

B1

This application is a divisional of U.S. Pat. No. 6,335,288, filed August 24, 2000.

Please amend the paragraph at p. 15, l. 25 – p. 16, l. 2 to read as follows:

B2

An example of a system that may incorporate some or all of the subsystems and routines described above would be the ULTIMA™ system, manufactured by APPLIED MATERIALS, INC., of Santa Clara, California, configured to practice the present invention. Further details of such a system are disclosed in commonly assigned U.S. Patent No. 6,170,428, filed July 15, 1996, entitled "Symmetric Tunable Inductively-Coupled HDP-CVD Reactor," having Fred C. Redeker, Farhad Moghadam, Hirogi Hanawa, Tetsuya Ishikawa, Dan Maydan, Shijian Li, Brian Lue, Robert Steger, Yaxin Wang, Manus Wong and Ashok Sinha listed as co-inventors, the disclosure of which is incorporated herein by reference. The described system is for exemplary purpose only. It would be a matter of routine skill for a person of skill in the art to select an appropriate conventional substrate processing system and computer control system to implement the present invention.

REMARKS

In the Office Action dated March 11, 2002 (paper no. 4), Claims 17 – 22 were rejected under 35 U.S.C. §103(a). These claim rejections are respectfully traversed. A copy of the claims pending is included in an Appendix.